ARTICLE

Received 20th October 2021, Accepted 00th January 20xx In-situ analysis of growth rate evolution during molecular layer deposition of ultra-thin polyurea films using aliphatic and aromatic precursors

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Supporting Information

FTIR analysis of the HDIC/ED film is conducted at different thicknesses between 5-50 nm thick. Results are shown in Fig. S1. The intensity of the associated polyurea peaks, detailed in Fig. 6 in the Results Section, grow with increasing film thickness. There is no significant shifting of the amide peaks (~1560 cm⁻¹ and ~1620 cm⁻¹) at these different thicknesses, indicating that for film thicknesses above 5 nm, the H-bonding strength within the film does not significantly change.



Sup. Fig. 1 FTIR spectra of HDIC/ED films measuring 5 nm (orange), 12 nm (green), and 50 nm (purple) thick deposited at 35 $^{\circ}$ C on hydroxylated SiO₂. Relevant polyurea peaks are highlighted.

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